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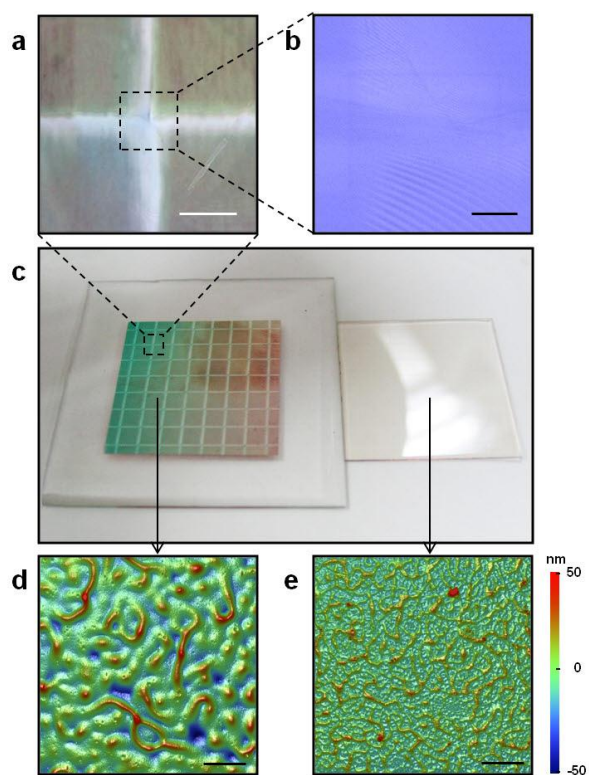
## Flexible organic light-emitting diodes using laser lift-off method

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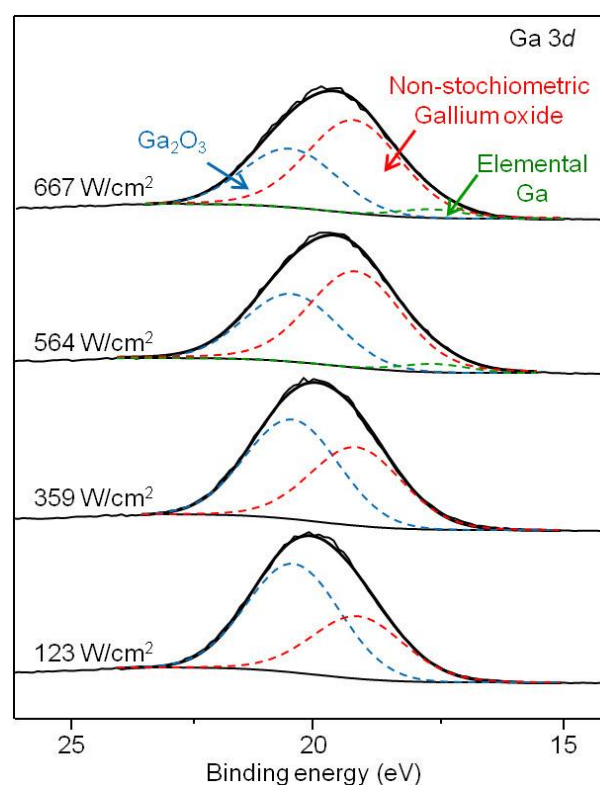
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**Fig. S1 AFM and SEM images before and after laser lift-off process.** **a.** Optical microscopy image of surface morphology on GaO<sub>x</sub> film after laser lift-off. Scale bar, 1 mm. **b.** SEM images. No cracks or damage occurred after two KrF excimer laser irradiations. A moiré pattern formed where the irradiated areas overlapped. Scale bar, 100 μm. **c.** A separated OLED sample (3 × 3 cm) and a carrier glass after laser lift-off. **d.** AFM phase image of the lower side of the device and **e.** the separated glass substrate after laser lift-off process. The average surface roughness was small (~0.7 nm) before laser lift-off, but increased to ~8.5 nm after lift-off. The sacrificial GaO<sub>x</sub> film was completely melted and separated without cracks by absorbing laser energy. AFM image size was fixed to be 5 μm × 5 μm. Scale bar, 1 μm

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**Fig. S2. SRPES spectra of Ga 3d<sub>5/2</sub> of GaO<sub>x</sub>.** Ga 3d<sub>5/2</sub> SRPES spectra of as-prepared GaO<sub>x</sub> film as a function of  $P_E$  and of laser irradiated GaO<sub>x</sub> film under OLED. The Ga<sub>2</sub>O component was rarely formed in special reduction ambient.  $2\text{Ga}_2\text{O}_3 \rightarrow \text{Ga}_2\text{O} + 2\text{Ga} + \text{O}_2$ . As  $P_E$  increased from 123 W/cm<sup>2</sup> to 893 W/cm<sup>2</sup>, the intensity ratio of Ga<sub>2</sub>O to Ga<sub>2</sub>O<sub>3</sub> increased from 0.28 to 0.67 and the full width at half maximum of GaO<sub>x</sub> samples expanded from 2.72 eV to 2.92 eV. A new Ga component was observed at  $P_E = 667$  W/cm<sup>2</sup> and the intensity of this component increased  $I_D$ .

### References

1. R. Carli and C. L. Bianchi, *Appl. Surf. Sci.*, 1994, **74**, 99-102.